



Dr. Hidetoshi Miyashita

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Title:

MEMS foundry Service in Sony Semiconductor Manufacturing Corp. and development of advanced process technology in collaboration with Tohoku University

Abstract:

Currently, Sony Semiconductor Manufacturing (SCK) provides MEMS foundry services and has experience in prototype development and mass production of various MEMS devices such as acoustic devices, gyroscope, optical MEMS, switches, mirror devices and so on. In order to continue to provide high value-added processes for customer devices, we are constantly striving to introduce new technologies. One example is the introduction of high vacuum encapsulation technology, which is currently being conducted in collaboration with Tohoku University with support from NEDO.

This presentation will also introduce this joint development.

Biography:

Hidetoshi Miyashita received his Ph.D. degree (2005), majoring in mechanical and electrical engineering, from the Tohoku University. Currently, Dr. Miyashita is an engineer of Device Engineering Department in SCK. He leads novel process introduction project in SCK. He also leads a project for mems tactile sensor with Sony R&D team. Before moving to SCK in 2016, he worked as an assistant professor at Tottori University. His research focused on chemical MEMS device with nanomaterials.